

Docket No. YO999-408CIP YOR.129CIP

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re patent application of

Cyril CABRAL, Jr., et al.

Serial No.: 09/902,483

Group Art Unit: 2813

Filed: July 11, 2001

Examiner: Kielin, Erik J.

For: SELF-ALIGNED SILICIDE (SALICIDE) PROCESS FOR LOW RESISTIVITY  
CONTACTS TO THIN FILM SILICON-ON-INSULATOR AND BULK  
MOSFETS AND FOR SHALLOW JUNCTIONS

Assistant Commissioner of Patents  
Washington, D.C. 20231



#19 / DS  
3-19-03  
RSTW

INFORMATION DISCLOSURE STATEMENT

Sir:

Under the provisions of 37 CFR §1.97 through §1.99 and pursuant to applicant's duty of disclosure under 37 CFR §1.56, applicant respectfully brings the following document listed on the attached form PTO-1449, to the attention of the Examiner in charge of the above-identified application. This reference was cited by the Examiner in co-pending Application No. 09/983,394, in an Office Action dated February 4, 2003. A copy of the listed document is provided herewith for the convenience of the Examiner.

This citation does not constitute an admission that the reference is relevant or material to the claims. It is only cited as constituting related art of which the applicant is aware.

I hereby certify that each item of information contained in this Information Disclosure Statement was the first citation of that item by the U.S.P.T.O. in a co-pending application, which occurred not more than three months prior to the filing of this statement.

It is respectfully requested that the listed references be considered by the Examiner and formally made of record in this application.

Please charge any deficiencies in fees and credit any overpayment of fees to Assignee's  
Deposit Account No. 50-0510.

Respectfully submitted,

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Date: 3/17/03

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